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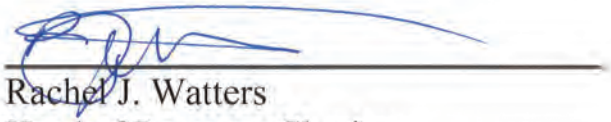
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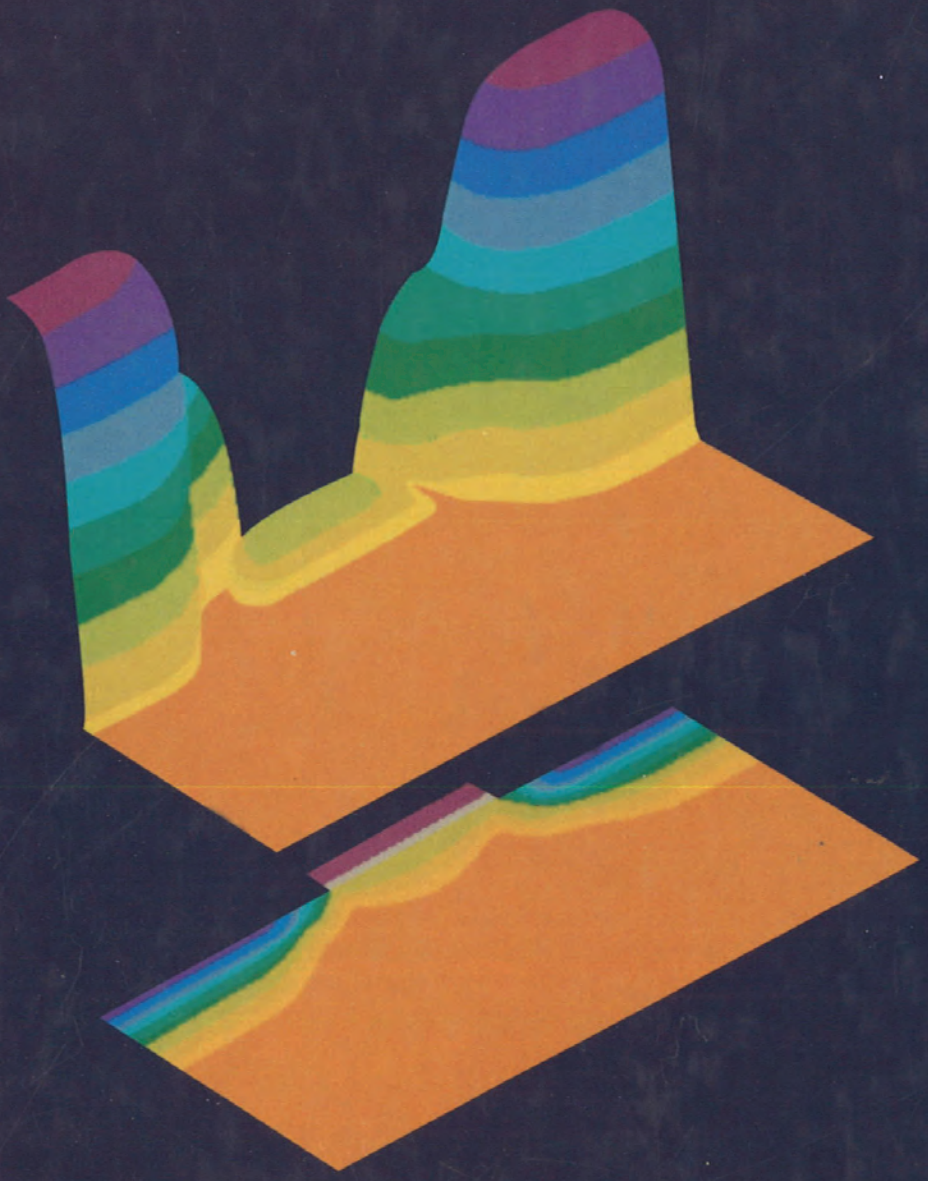
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1986 LATTICE PRESS 660 pp. ISBN 0-9616721-3-7

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By STANLEY WOLF

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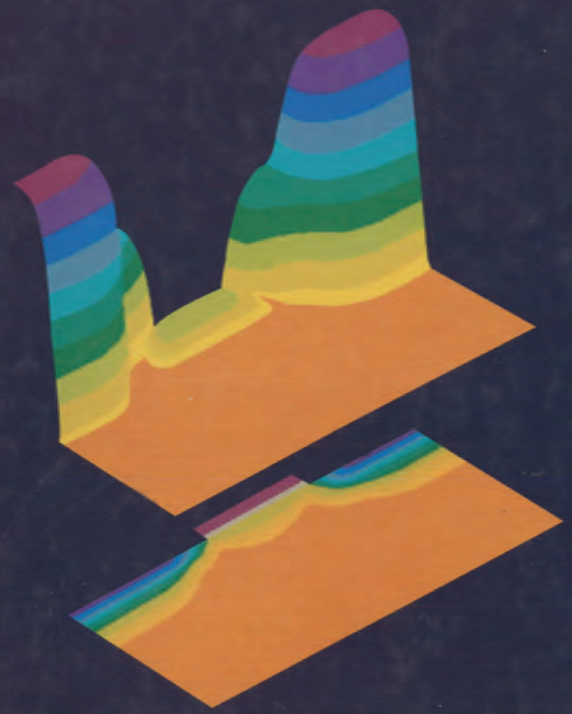
Silicon Processing
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Volume 3
The
Submicron
MOSFET

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FOR

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VOLUME 3:

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STANLEY WOLF Ph.D.
Professor, Department of Electrical Engineering
California State University, Long Beach
Long Beach, California

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Material type	Book
Item policy	general (book)
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Is magnetic	No
PO Line	
Issue date	-
Receiving date	02/12/2002
Expected receiving date	-
Enumeration A	3
Enumeration B	-
Chronology I	-
Chronology J	-
Description	3
Pages	-
Pieces	1
Replacement cost	-
Receiving operator	import
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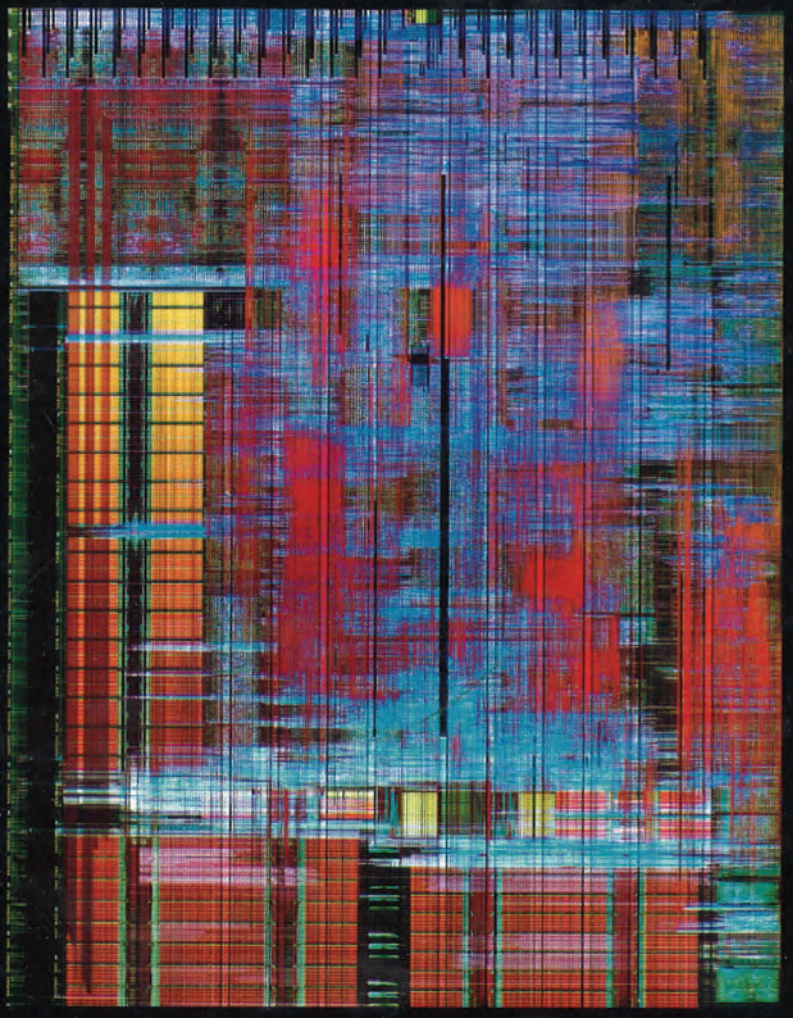
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BEN G. STREETMAN ▪ SANJAY BANERJEE

Prentice Hall Series in Solid State Physical Electronics, Nick Holonyak, Jr., Series Editor

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- completely updated discussion of MOS devices, both in the underlying theory as well as discussion of short channel, high field and hot carrier effects in scaled MOSFETs, recognizing the current preponderance of CMOS.
- updated, consolidated treatment of optoelectronic devices, including sources such as blue GaN-based LEDs and semiconductor vertical-cavity surface-emitting lasers, as well as detectors such as avalanche and resonant-cavity photodiodes.
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- about 200 problems and current references which extend concepts in the text.



BEN G. STREETMAN is Dean of the College of Engineering at The University of Texas at Austin and holds the Dula D. Cockrell Centennial Chair in Engineering. He is a Professor of Electrical and Computer Engineering and was the founding Director of the Microelectronics Research Center. He has taught at the University of Illinois at Urbana-Champaign as well as the University of Texas at Austin. He has received numerous awards including the Education Medal of IEEE, The Frederick Emmons Terman Medal of the ASEE, and membership in the National Academy of Engineering. He has published more than 270 articles in the technical literature. Thirty-three students of Electrical Engineering, Materials Science, and Physics have received their Ph.D.s under his direction.



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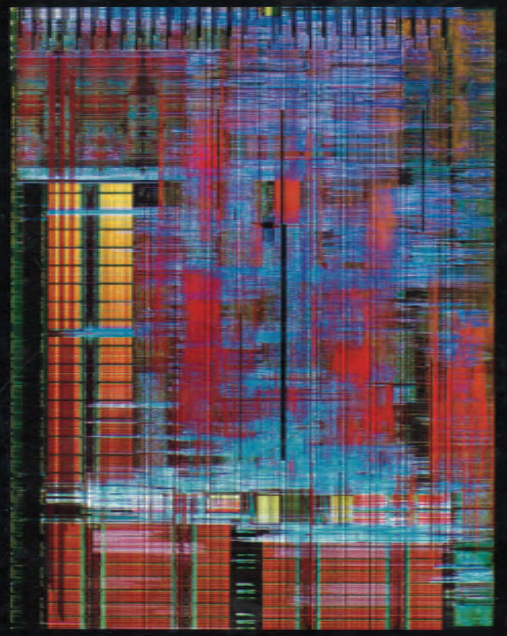
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Solid State Electronic Devices

BEN G. STREETMAN AND SANJAY BANERJEE

Microelectronics Research Center
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Temporary location

Temporary call number type

Temporary call number

Temporary source (Subfield 2)

Temporary item policy

Due back date

Retention Information

Committed to Retain No Yes

Retention Reason

Retention Note

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